

ABSTRACT OF THE DISCLOSURE

In an electron beam apparatus including an electron source and an electron beam irradiation member, a potential specifying plate including 5 openings through which an electron transmits is provided between the electron source and the electron beam irradiation member. A spacer is located between the electron beam irradiation member and the potential specifying plate. In the case where a 10 distance between a region between one of the openings of the potential specifying plate which is near the spacer and the spacer and the electron beam irradiation member is given by D1 and a distance between a region between the one opening of the 15 potential specifying plate which is near the spacer and another opening thereof which is not near the spacer and the electron beam irradiation member is given by D2, if $D1 < D2$ is satisfied, a deviation of an orbit of an electron beam emitted from the 20 electron source is suppressed, so that it is possible to produce a high quality image.